

Vintage: Dec. 2008

Wafer Size: 300mm

SW Version: 5.1.0.b

Main Process: Photo

Sub-Process: ARF-Scanner



(2) Hardware Configuration:

	Moudule	Check Items	Yes or No	Remarks
1	OIU	Is the motherboard complete?	✓	
2		Are the keyboard, mouse, and monitor working?	✓	
3	WH	Hardware defects or damage	X	
4		Are there any scratches or dirt on the component gripper or TSU surface?	X	
5	WS	Hardware defects or damage	X	
6		Are there any scratches or dirt on the surface of the component Closing Disk?	✓	A little bit of particle water stain attached on holder
7		Are there any scratches or dirt on the surface of the mirror block components?	✓	A little bit of particle water stain
8		Are there any scratches or dirt on the Z-mirror component surface?	✓	A little scratch M-side water stain
9		Are there any scratches or dirt on the surface of the image sensor components?	✓	A little bit of particle water stain
10		Are there any scratches or dirt on the surface of the wafer table component?	✓	wafer on table
11	RH	Hardware defects or damage	✓	T-bar missing backboard cover missing 2pcs
12	RS	Hardware defects or damage	X	
13		Are there any scratches or dirt on the R-chuck component surface?	✓	A little bit of particle
14	ILL	Hardware defects or damage	X	
15		Does the surface of the REMA lens have any scratches or dirt?	X	
16		Is there a number of Bending Points?	X	

17	Lens	Hardware defects or damage	X	
18		Are there any scratches or dirt on the top and bottom of the lens?	✓	A little particle
19		Is the sensor on the top of the lens complete?	✓	
20	EIM	Hardware defects or damage?	X	
21		Hardware defects or damage?	✓	298
22	LMA&AOM	Hardware defects or damage?	X	
23	ELEC	Hardware defects or damage?	X	
24	WSRC	Hardware defects or damage?	X	
25	RSRC	Hardware defects or damage?	X	
26	ACC	Hardware defects or damage?	X	
27	LCWC	Hardware defects or damage?	✓	monitor broken
28	MCWC	Hardware defects or damage?	X	
29	WICC	Hardware defects or damage?	X	
30	WISC	Hardware defects or damage?	X	
31	Laser	Hardware defects or damage?	X	MODEL: Cymer XLA360 2006 3/22

System safely powered down

TWINSKAN XT-1700Fi SYSTEM ACCEPTANCE TESTS

Category		Items	Spec	Model: XT1700Fi
		Full Acceptance Test	XT1700Fi	Result-Data
1. Overlay		1.1 Single machine overlay	≤ 5	NA
2. Intensity		2.1 Slit integrated power, 11 scans in 26mm Setting 1 [mW/cm]		NA
3. Projection Lens		3.1 RMS Z5-Z37 [nm]	≤ 1.4	2.66
		3.2 RMS Spherical [nm]	≤ 0.8	0.65
		3.3 RMS coma [nm]	≤ 0.8	0.84
		3.4 RMS astigmatism [nm]	≤ 0.8	0.54
		3.5 RMS 3-foil [nm]	≤ 0.8	0.71
		3.6 Long range straylight [SAMOS %]	≤ 0.9	NA
		3.7 Short range straylight [SAMOS %]	≤ 1.2	NA
4. Illumination		4.1 Dose system performance, setting 1 [%]	≤ 1.0	NA
		4.2 Integrated slit uniformity, setting 1 [%]	≤ 0.30	NA
		4.3 Integrated scan uniformity, setting 1 [%]	≤ 0.2	NA
		4.4 Dose repeatability [%]	≤ 0.2	NA
		4.5 Dose accuracy setting 1 [%]	± 0.7	NA
5. Pupil Verification		5.1 Ellipticity, Setting 1 [meam]	≤ 1.5	NA
		5.2 Sigma variation setting 1 [range]	≤ 0.007	NA
6. Focus and Leveling		6.1 Wafer map repeatability (99.7%) [nm]	≤ 8	NA
7. Dynamic Performance		7.1 MA X&Y (mean+3ig) [nm]	≤ 2.0	NA
		7.2 MSD X&Y (max of mean per field) [nm]	≤ 6.5	NA
		7.3 Inspection time (<200 particles found) [nm]	≤ 225	NA
		7.4 Size accuracy - latex spheres () Upper surface		
		10um [um]	± 3	NA
		30um [um]	± 3	NA
		50um [um]	± 5	NA
		7.5 Size accuracy - latex spheres () Lower surface		
		10um [um]	± 3	NA
		30um [um]	± 3	NA
		50um [um]	± 5	NA
8. BMWL - fine		Test results		NA
9. ISPE		Test results		NA
10. SWZS		Test results		NA